

THIN FILM DEPOSITION

Odyssey 450 Deposition System



The Odyssey 450 delivers the results you expect with the trusted support of a market leader.

The Odyssey 450 is the perfect solution for those needing small-scale production with the high quality results of a large, sophisticated system. Whether it's pilot production or R&D, the Odyssey's versatile design supports many types of deposition methods to produce highly efficient, uniform thin films for even the most complex applications.

The Odyssey's base system comes equipped with a 450mm vacuum chamber, pumping system, and Dynavac's LabVIEW-based supervisory control system, all housed in a portable, modular cabinet. Choose just the right process equipment from a comprehensive package of deposition sources, tooling configurations, and thickness control methods. The Odyssey's flexible design platform also makes re-tooling possible to support future process applications, maximizing your investment for years to come.

The Odyssey 450 is part of Dynavac's complete platform of resources to support you from initial design through everyday operation. Process development support is available through our team of process engineers and our dynamic customer support team ensures your investment is protected through the life of your equipment.

Base System

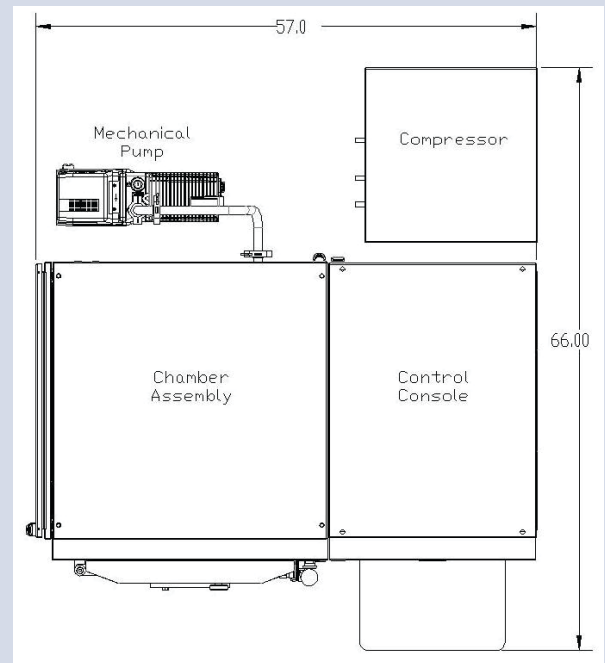
- Vacuum Chamber
 - 450mm w x 450mm d x 600mm h stainless steel chamber
 - Full opening front door with 4" viewport
- Pumping System
 - Turbomolecular pump or cryopump for high vacuum pumping
 - Rotary vane pump for chamber roughing
- Controls & Instrumentation
 - PLC with LabVIEW interface
 - Power distribution system
 - Vacuum gauge package
- Startup & Training
 - Pre-shipment startup & training

Available Options

- Vacuum Chamber
 - Water-cooling
 - Additional ports for customer use
- Pumping System
 - Dry mechanical pump
- Substrate Fixturing
 - Single rotation fixture (multiple configurations)
 - Planetary mechanism
 - Static fixture
- Process Equipment
 - Electron beam source
 - Resistance evaporation source
 - Ion source
 - Substrate heat
 - Single or multiple sputter cathodes
 - RF / DC / Pulsed power supplies
 - Glow discharge system
 - Process gas control
- Controls & Instrumentation
 - Enhanced control system (data logging, trending, etc.)
 - Quartz crystal monitor
 - Dynavac Spectrum Pro Optical Monitor
 - Residual gas analyzer
 - Plasma emission monitor
- Startup & Training
 - Onsite installation, startup, & training



Rear Internal View



Floor Layout